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PATENT  
1691-0170P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: WAKAMATSU, Satoru et al.

Int'l. Appl. No.: PCT/JP01/03865

Appl. No.: New Group:

Filed: January 11, 2002 Examiner:

For: POLYCRYSTALLINE SILICON, METHOD AND APPARATUS FOR PRODUCING THE SAME

PRELIMINARY AMENDMENT

**BOX PATENT APPLICATION**

Assistant Commissioner for Patents  
Washington, DC 20231

January 11, 2002

Sir:

The following Preliminary Amendments and Remarks are respectfully submitted in connection with the above-identified application.

AMENDMENTS

IN THE SPECIFICATION:

Please amend the specification as follows:

Before line 1, insert --This application is the national phase under 35 U.S.C. § 371 of PCT International Application No. PCT/JP01/03865 which has an International filing date of May 9, 2001, which designated the United States of America.--